OPTOFLUX

MSP1232

Training Syllabus

Task	Day
System Overview	
Describe the system & process (1h)	1
Explain the components of the process module (1h)	1
Describe the vacuum system (1h)	1
Describe the system facilities (1h)	1
Safety	
Read chapter "Safety" of MSP Operating Instructions (1)	1
GUI Software	
Explain the design of the system control hardware (0.5h)	1
Login/logout KHAN GUI, select the operating mode (0.5h)	1
Describe the KHAN screens accessible in manufacturing mode (2h)	1
Demonstrate use of the online help (0.5h)	1

Production Start	
Check the prerequisites for production start (0.5h)	2
Open and close the process chamber (0.5h)	2
Reload the substrate carrier (0.5h)	2
Replace the GSM monitor glass (0.5h)	2
Run a process (0.5h)	2
Maintenance	
Execute the process chamber maintenance (1h)	2
Execute the cathode maintenance (1h)	2
Execute the plasma source maintenance (1h)	2
Process training	
Describe the principle of reactive sputtering (1h)	3
Explain function and integration of Plasma Emission Monitor (1h)	3
Create a KHAN recipe for a 2 layer deposition (2h)	3
Explain the GSM system (3h)	3
Explain target material specific process parameters (2h)	3
Use the “Strategy Generator” to create a new recipe (4h)	4
Optimize film thickness uniformity by using “Uni Tune” (4h)	4
Reserve	
Various	5